

WHAT IS CLAIMED IS:

1. A multibeam generating apparatus for generating a plurality of electron beams, comprising:
  - a plurality of electron generators;
  - 5 an acceleration electrode which forms an acceleration field for accelerating an electron emitted from each one of said plurality of electron generators; and
  - a shield electrode at least part of which is
- 10 arranged between said plurality of electron generators and said acceleration electrode.
2. The apparatus according to claim 1, wherein at least part of said shield electrode is arranged between a trajectory of the electron emitted from said each one of said electron generators and an electron generator near said each one of said electron generators.
- 15 3. The apparatus according to claim 1, wherein each one of said electron generators comprises
  - a cathode electrode for emitting the electron and
  - 20 a Wehnelt electrode.
4. The apparatus according to claim 3, wherein said shield electrode comprises a plate-like electrode having an opening for passing the electron therethrough.
- 25 5. The apparatus according to claim 4, wherein a thickness of said plate-like electrode is not more than 1/10 a gap between said Wehnelt electrode and said

acceleration electrode.

6. The apparatus according to claim 4, wherein a gap between said Wehnelt electrode and said plate-like electrode is smaller than a gap between said plate-like 5 electrode and said acceleration electrode.

7. The apparatus according to claim 4, wherein a gap between said Wehnelt electrode and said plate-like electrode is not more than 1/4 a width of said Wehnelt electrode in a direction perpendicular to a trajectory 10 of an electron beam.

8. The apparatus according to claim 4, wherein a potential, for a set position of said plate-like electrode, which is determined by a potential of said Wehnelt electrode and a potential of said acceleration 15 electrode is applied to said plate-like electrode.

9. The apparatus according to claim 3, comprising, outside an outermost Wehnelt electrode of an array of Wehnelt electrodes in said plurality of electron generators, an electrode for correcting characteristics 20 of said outermost Wehnelt electrode.

10. The apparatus according to claim 1, wherein said shield electrode has wall portions arranged among said plurality of electron generators.

11. The apparatus according to claim 1, wherein said 25 shield electrode has a plurality of cylindrical inner surfaces each surrounding a trajectory of the electron emitted from said each one of said plurality of

electron generators.

12. The apparatus according to claim 1, wherein said acceleration electrode is provided to be common among said plurality of electron generators.

5 13. The apparatus according to claim 1, wherein said shield electrode is provided to be common among said plurality of electron generators.

14. The apparatus according to claim 1, wherein said acceleration electrode and said shield electrode are 10 provided to be common among said plurality of electron generators.

15. An electron beam drawing apparatus comprising:  
the multibeam generating apparatus according to  
claim 1; and

15 a lens for projecting the plurality of electron beams generated by the multibeam generating apparatus onto a substrate.